

METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
LIFT-OFF OF POROUS SILICON LAYERS
Solanki, et al.
Appl. No.: Unassigned Atty Docket: IMEC197.001CP1

PRIOR ART

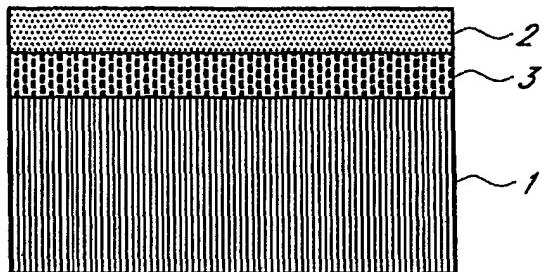


FIG. 1A

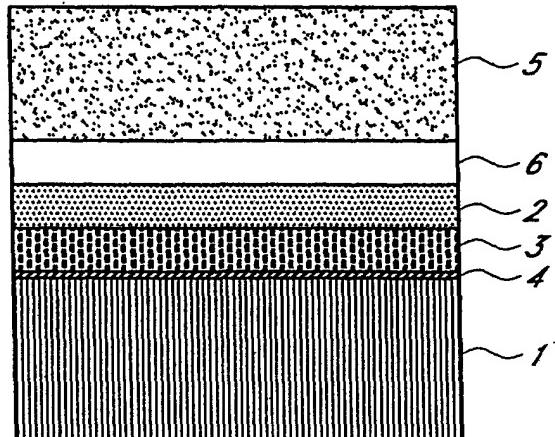


FIG. 1D

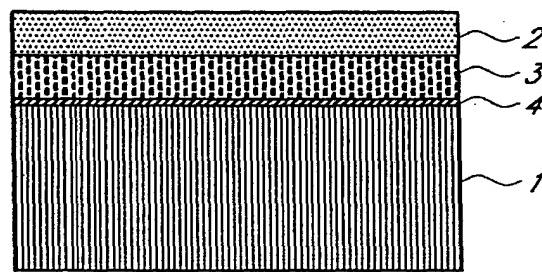


FIG. 1B

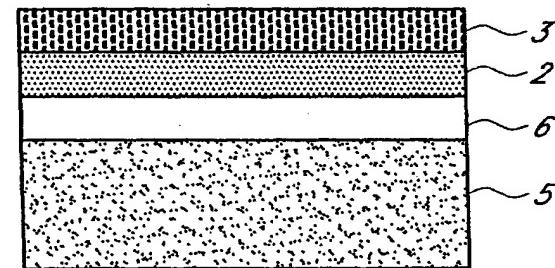


FIG. 1E



FIG. 1C

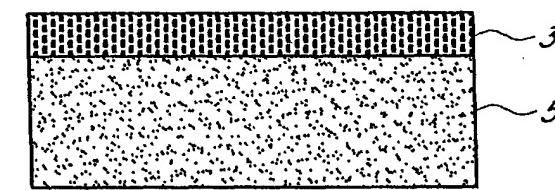


FIG. 1F

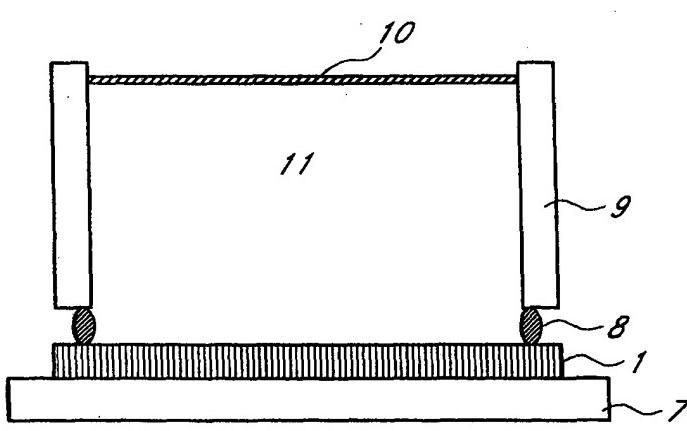


FIG. 2

*METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
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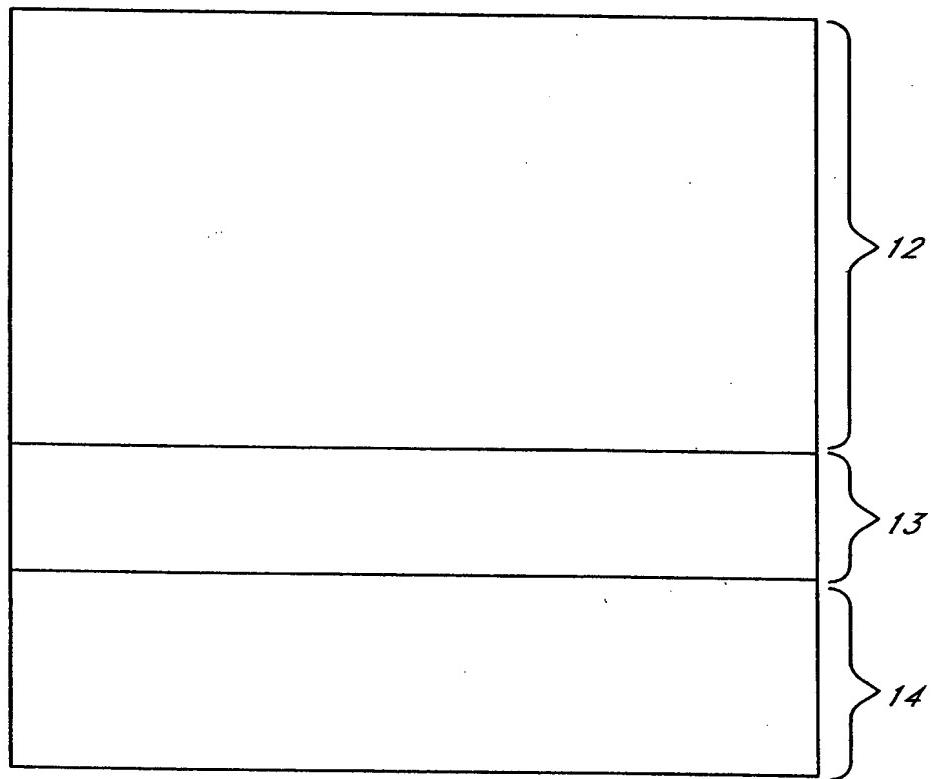


FIG. 3A

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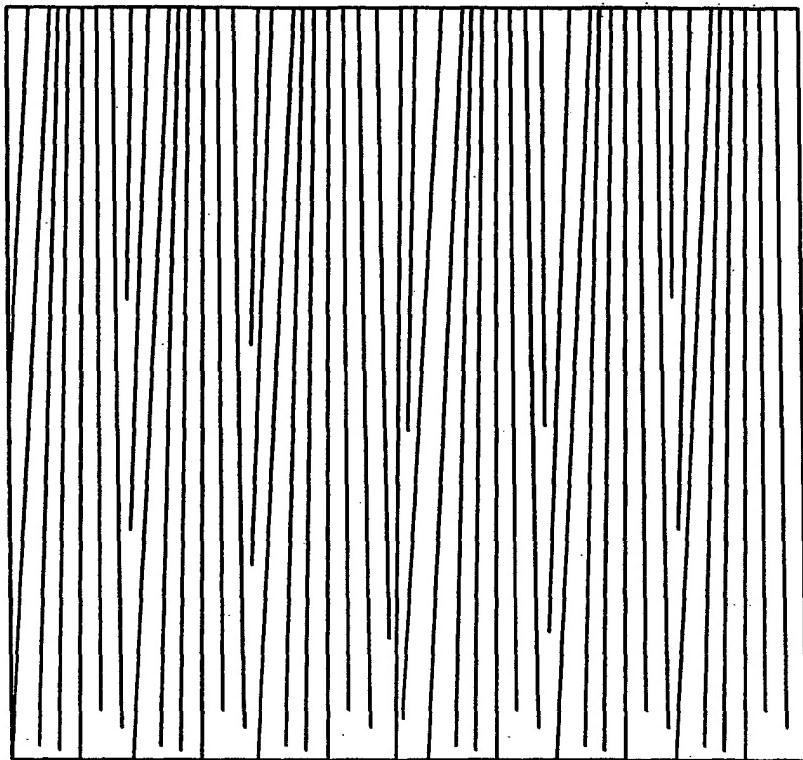


FIG. 3B

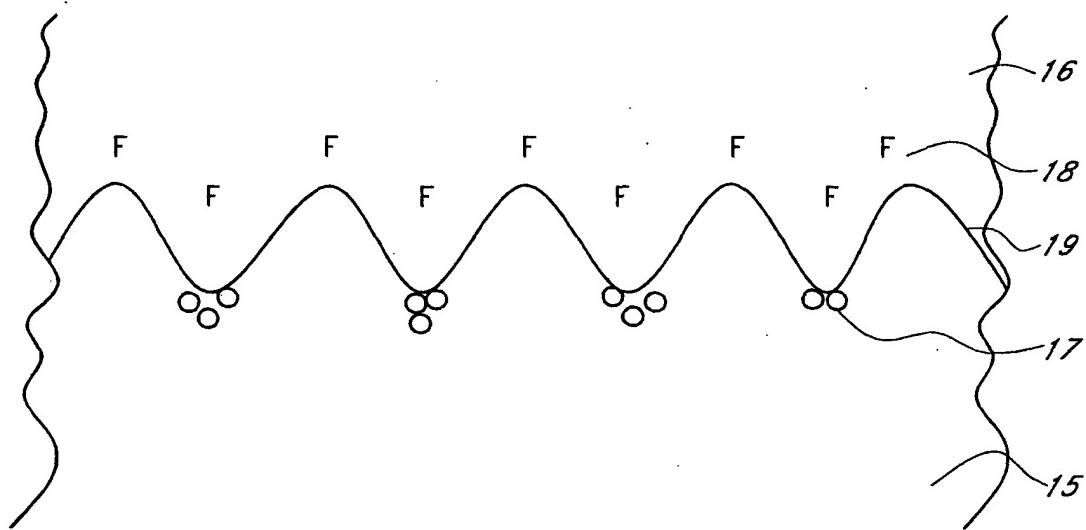


FIG. 4

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FIG. 5A

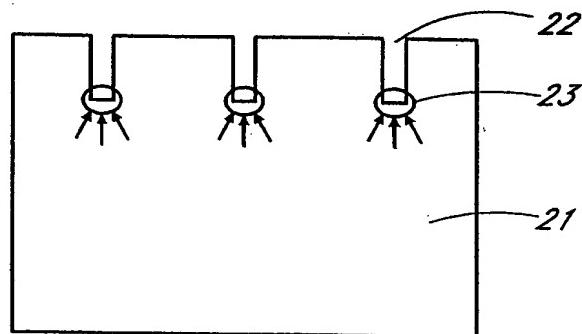


FIG. 5B

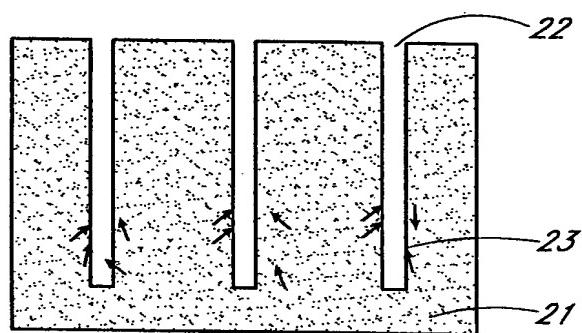


FIG. 5C

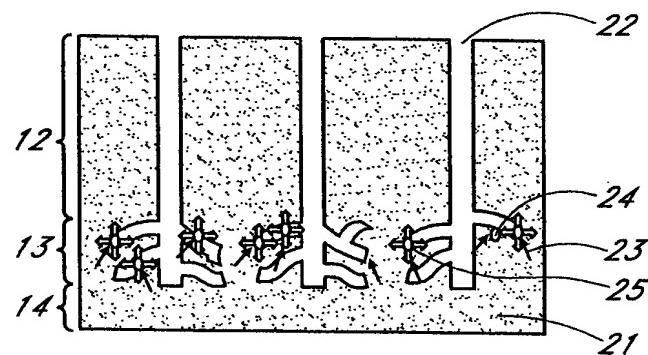
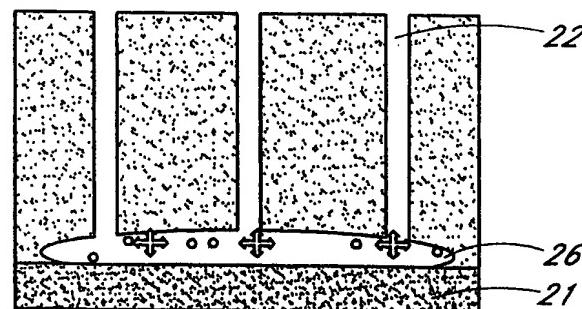


FIG. 5D



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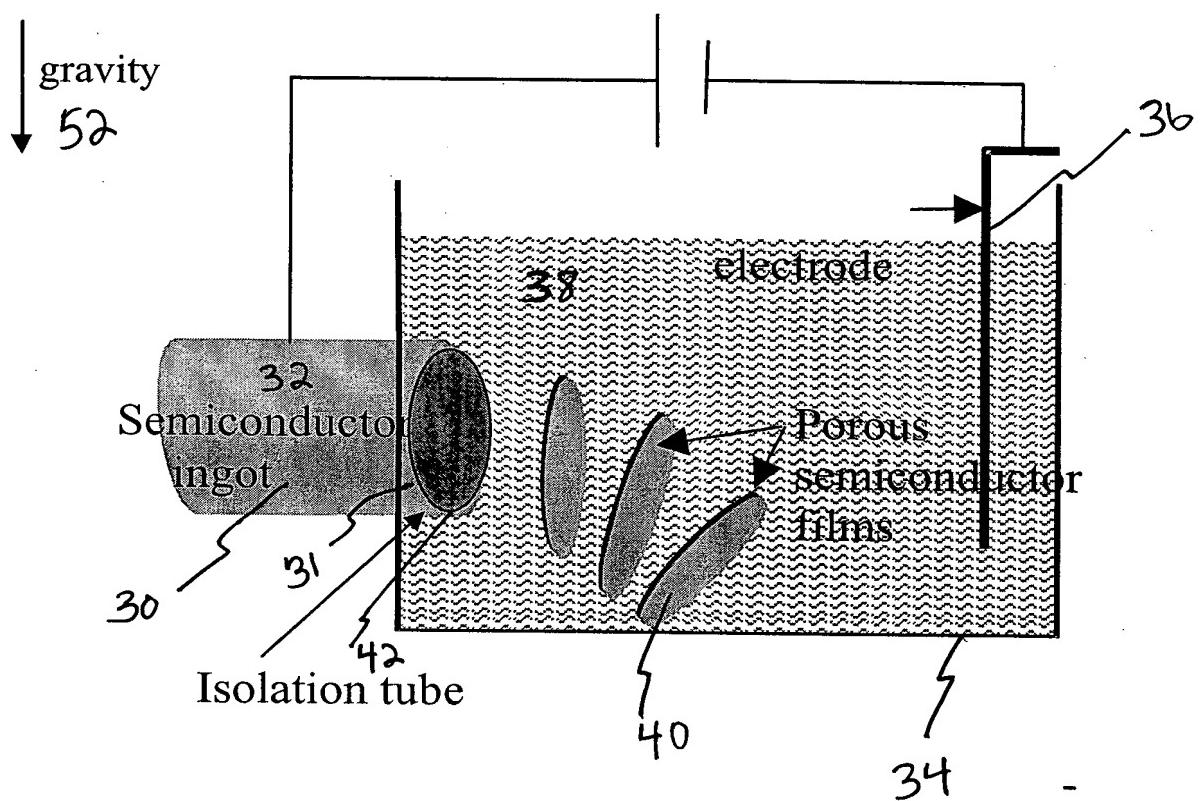
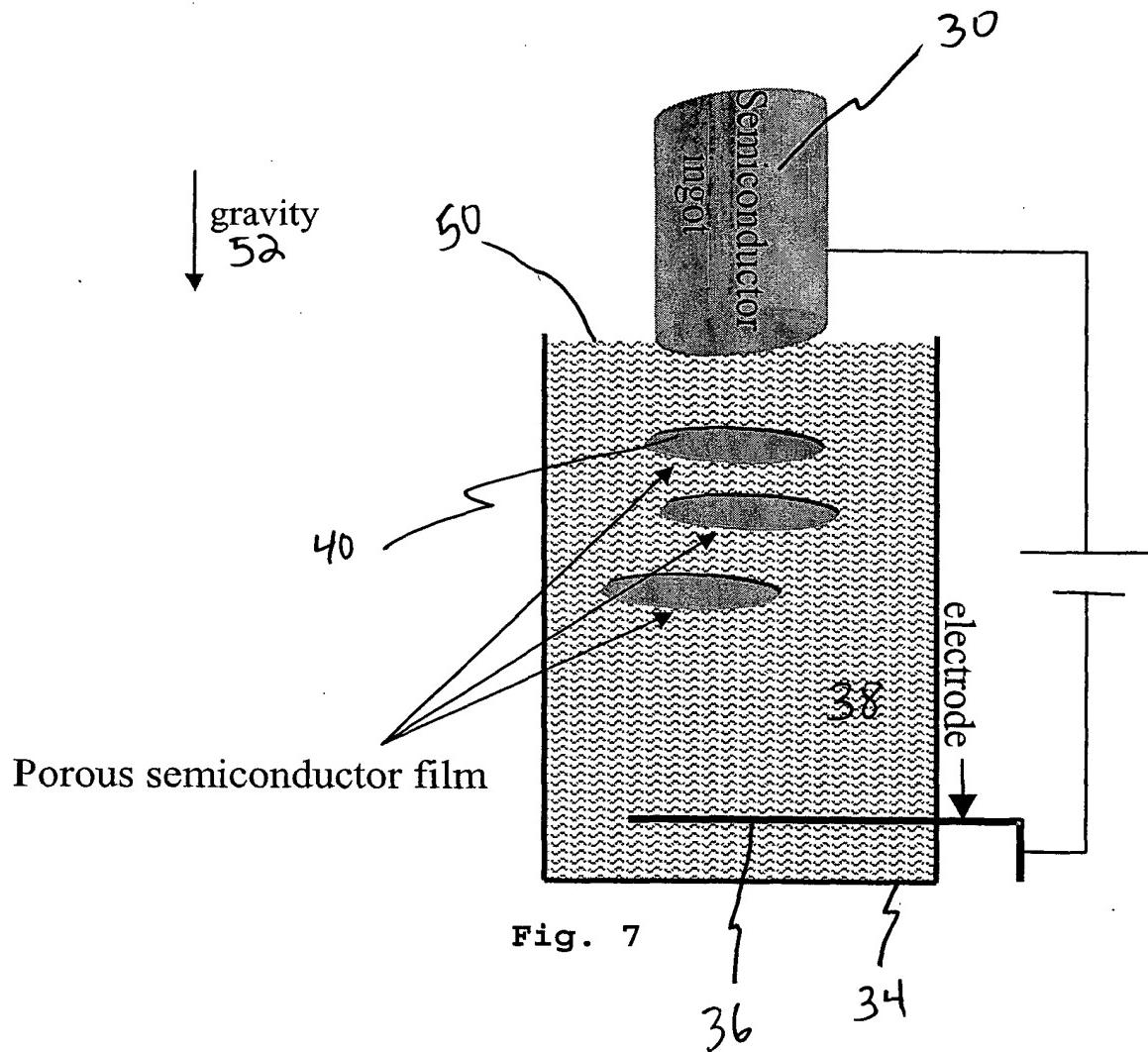


Fig. 6

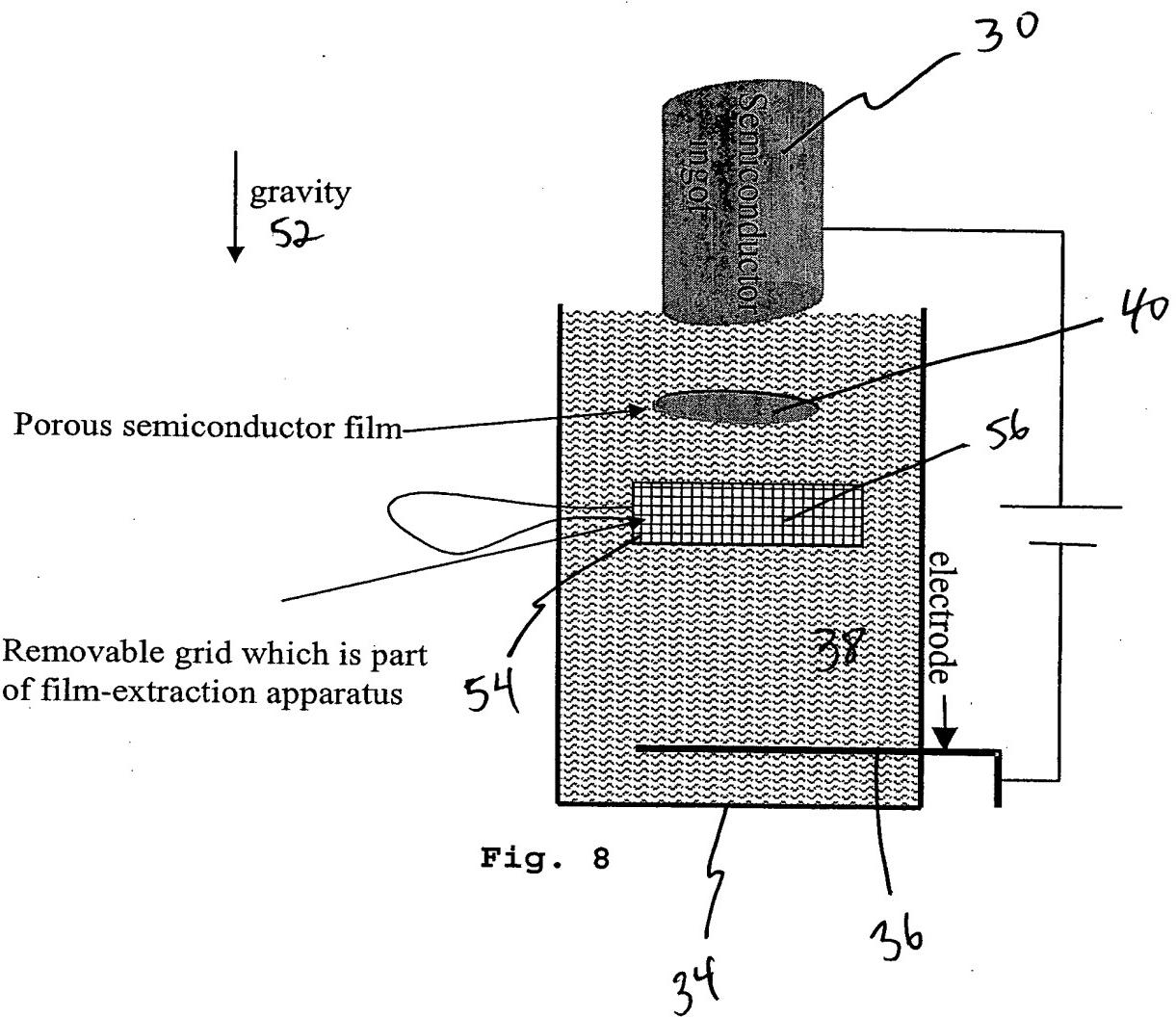
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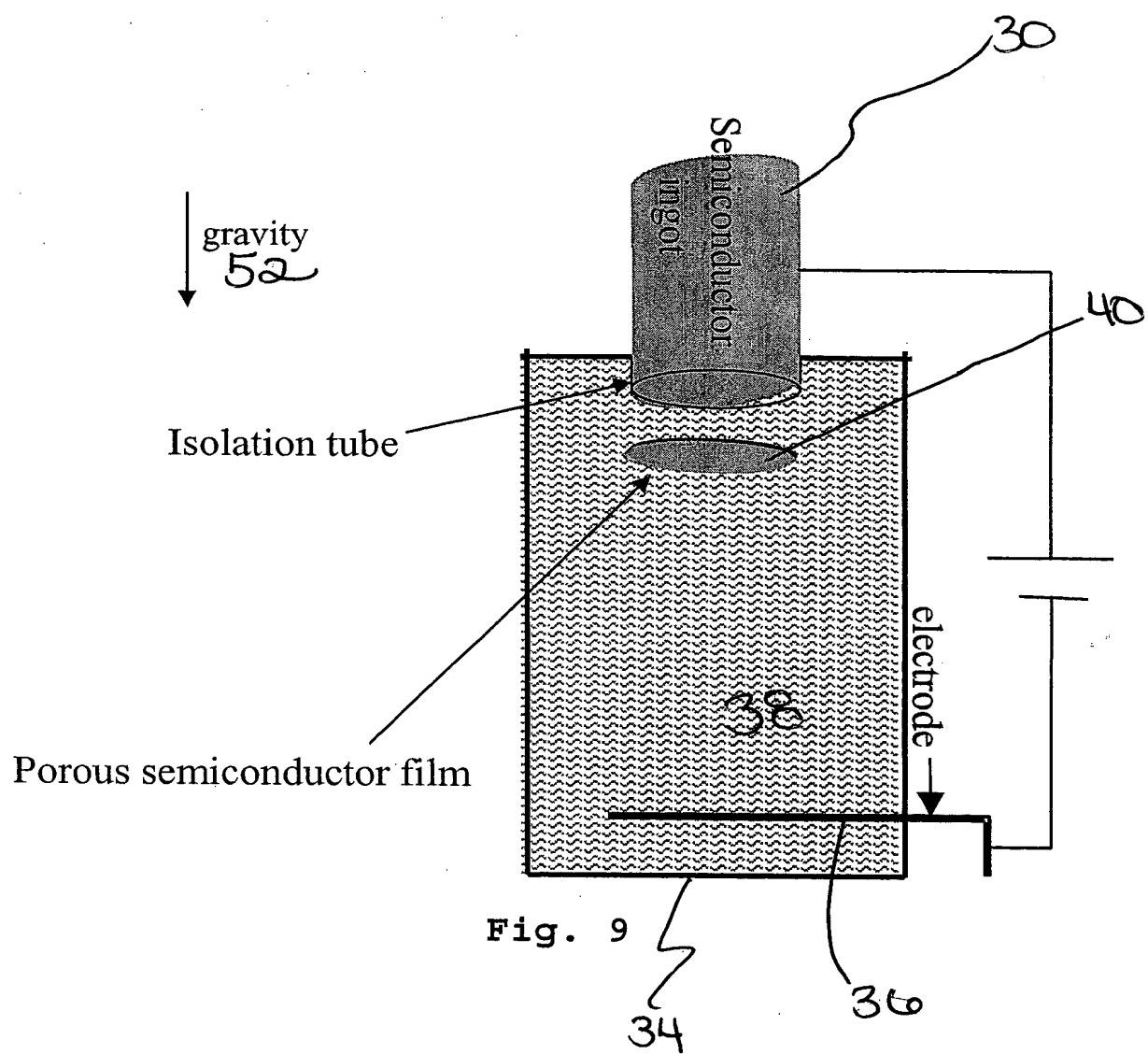
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Fig. 10a

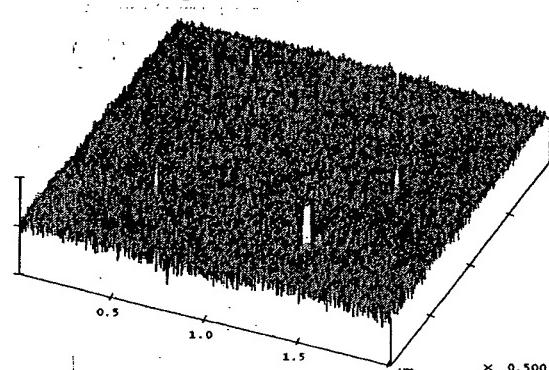


Fig. 10b

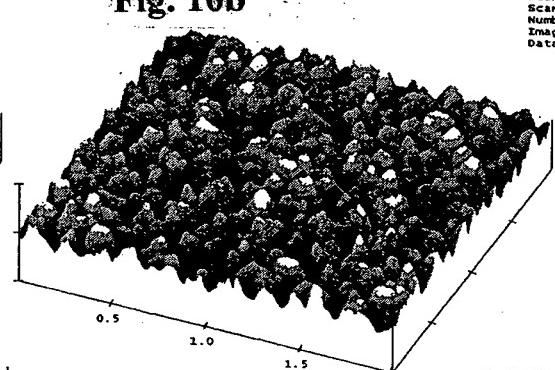


Fig. 10c

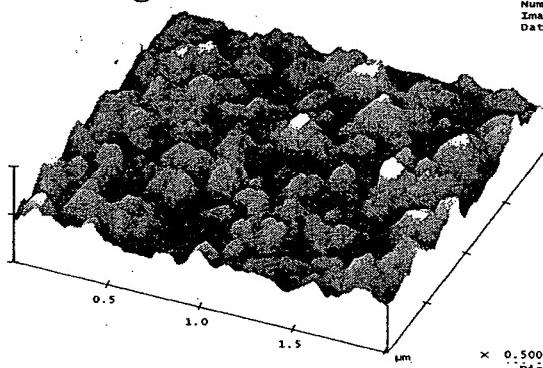


Fig. 10d

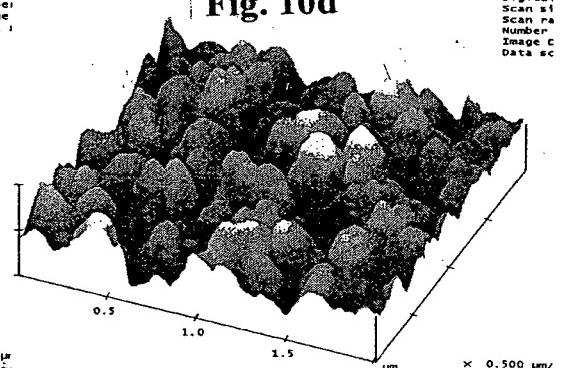


Fig. 10e

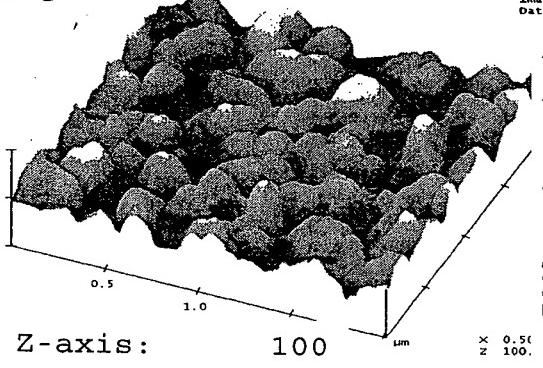


Fig. 10f

